


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/678,045 Confirmation No. : 6655
First Named Inventor : Hiroshi SHINRIKI
Filed : October 3, 2003
TC/A.U. : 1762
Examiner : B. P. Chen
Docket No. : 010986.52822US
Customer No. : 23911
Title : Removing Oxide Film on a Substrate with Hydrogen and Fluorine Radicals



AMENDMENT AFTER FINAL UNDER 37 C.F.R. §1.116

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria , VA 22313-1450

Sir:

The following proposed amendments and remarks are respectfully submitted in response to the final Office Action dated November 2, 2005.

Amendments to the Claims are reflected in the listing of claims beginning on page 2 of this paper.

Remarks begin on page 4 of this paper.